

INTERNATIONAL TECHNOLOGY ROADMAP FOR SEMICONDUCTORS

2004 UPDATE

RF and Analog/Mixed-signal Technologies for Wireless Communications

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RF AND ANALOG/MIXED-SIGNAL TECHNOLOGIES FOR WIRELESS COMMUNICATIONS

2004 UPDATE HIGHLIGHTS

Analog and Mixed Signal: The technology requirements are now aligned for analog speed devices with the LSTP roadmap instead of, as in the past, with the LOP roadmap. It is becoming more challenging to keep a constant ratio of transconductance g_m to drain conductance g_{ds} for high performance analog devices in new technologies. The challenges for reducing $1/f$ noise in high-k gate dielectrics are relaxed to a color coding of "yellow" from "red." However, $1/f$ noise in high-k gate dielectrics still remains challenging. The published reports about solutions for high density capacitors meeting density, leakage, and matching specifications suggested changes to capacitor color coding for the 2004 ITRS update from red to yellow for the years 2013 to 2016.

RF Transceivers: Similar to the Near Term Table, a lag between RFCMOS gate length and BiCMOS gate length now occurs in the Long Term Table. For RFCMOS, the technology requirements maintained one-year lag from the LSTP CMOS roadmap.

Power Amplifiers & Power Management: The major trends appear to have been correctly anticipated in 2003 for handsets. The first two RFCMOS Dual Band GSM power amplifiers (PAs) were sampled by cellular customers in 2004. These PAs are not expected to be players in the market until 2005. However, RFCMOS PAs could play a major role in 2006. The success of RFCMOS PA's may erode price margins at a faster rate than anticipated. Multi-band cellular SiGe PAs also are being sampled. Highly integrated modules with multi-layer laminates of low temperature cindered ceramics (LTCC) are dramatically reducing total RF front-end area. The cost (\$\$/Watt) for basestation PAs will decrease more rapidly than shown in the 2003 Roadmap and are expected to reach \$0.40 per watt in 2008. Saturated power density (W/mm) of all technologies will increase more rapidly and will reach 1.4 W/mm, 1.8 W/mm, 3 W/mm, and 5 W/mm by 2008 for LDMOS, GaAs, SiC, and GaN, respectively. Manufacturing solutions now exist for 28V GaAs FET's, 60W SiC FET's, and 28 V GaN FET's. Linear operation is expected to achieve less than half the RF power of saturated operation. In the 2003 Roadmap, linear operation was expected to achieve half the RF power of saturated operation.

Millimeter Wave (10-100GHz): There are no major changes for the 2004 Update. InP HBTs are expected to advance more quickly due to aggressive R&D funding than they were predicted to do so in the 2003 ITRS. The 2005-2006 color coding for all InP HBT device requirements are changed from yellow to white. Also, the 2007-2008 figures of merit for device f_T and f_{MAX} are more aggressive. Copper interconnects are expected to be introduced in 2007. The use of today's gold and aluminum interconnects is expected to continue until at least 2009.

[Link to the 2003 ITRS RF and Analog/Mixed-signal Technologies for Wireless Communications chapter](#)

WORKING GROUP TABLES

Table 53a Analog and Mixed-signal Devices Technology Requirements—Near-term **UPDATED**

	[1]	Year of Production	2003	2004	2005	2006	2007	2008	2009	
		Technology Node		hp90			hp65			
		DRAM ½ Pitch (nm)	100	90	80	70	65	57	50	
WAS	[2]	Minimum Supply Voltage	Digital design (V)	1	1	0.95	0.9	0.85	0.8	0.75
IS	[2]	<u>nMOS Analog Speed Device</u>	<u>Supply voltage (V)</u>	<u>1.5</u>	<u>1.2</u>	<u>1.2</u>	<u>1.2</u>	<u>1.1</u>	<u>1.1</u>	<u>1.1</u>
WAS**	[3]	Minimum Supply Voltage	Analog design (V)	3.3–1.8	2.5–1.8	2.5–1.8	2.5–1.8	2.5–1.8	2.5–1.8	2.5–1.8
IS	[7]	<u>entire row MOVED**</u>	<u>Supply voltage (V)</u>							
WAS	[4]	NMOS Analog Speed Device	T_{ox} (nm)	1.2–1.8	1.1–1.6	1.1–1.6	1.1–1.6	0.7–1.2	0.7–1.2	0.7–1.2
IS	[3]	NMOS Analog Speed Device	T_{ox} (nm)	2.3	<u>2.1</u>	<u>2.1</u>	1.9	1.6	1.5	1.4
WAS	[5]	NMOS Analog Speed Device	g_m/g_{ds} at $5 \cdot L_{min}$ -digital	100	100	100	100	100	100	100
IS	[4]	NMOS Analog Speed Device	g_m / g_{ds} @ $5 \cdot L_{min}$ -digital	100	100	100	100	<u>100</u>	<u>100</u>	<u>100</u>
WAS	[6]	NMOS Analog Speed Device	$1/f$ -noise ($\mu V^2 \cdot \mu m^2 / Hz$)	300	200	200	200	150	150	150
IS	[5]	NMOS Analog Speed Device	$1/f$ -noise ($\mu V^2 \cdot \mu m^2 / Hz$)	300	200	200	<u>200</u>	<u>150</u>	<u>150</u>	<u>150</u>
WAS	[7]	NMOS Analog Speed Device	σV_{th} matching (mV· μm)	5	4	4	4	3	3	3
IS	[6]	NMOS Analog Speed Device	σV_{th} matching (mV· μm)	5	4	4	4	<u>3</u>	<u>3</u>	<u>3</u>
MOVED**	[7]	<u>nMOS Analog Precision Device</u>	<u>Supply voltage (V)</u>	<u>3.3-1.8</u>	<u>2.5 - 1.8</u>	<u>2.5 - 1.8</u>	<u>2.5 - 1.8</u>	<u>2.5 - 1.8</u>	<u>2.5 - 1.8</u>	<u>2.5 - 1.8</u>
WAS	[8]	nMOS Analog Precision Device	T_{ox} (nm)	6.5–3	6.5–3	6.5–3	6.5–3	5–3	5–3	5–3
IS	[8]	nMOS Analog Precision Device	T_{ox} (nm)	6.5-3	<u>5 - 3</u>	<u>5 - 3</u>	<u>5 - 3</u>	5 - 3	5 - 3	5 - 3
WAS	[9]	nMOS Analog Precision Device	Analog V_{th} (V)	0.5–0.3	0.5–0.2	0.4–0.2	0.4–0.2	0.4–0.2	0.3–0.2	0.3–0.2
IS	[9]	nMOS Analog Precision Device	Analog V_{th} (V)	0.5-0.3	<u>0.4 - 0.2</u>	0.4 - 0.2	0.4 - 0.2	<u>0.3 - 0.2</u>	0.3 - 0.2	0.3 - 0.2

Manufacturable solutions exist, and are being optimized

Manufacturable solutions are known

Interim solutions are known

Manufacturable solutions are NOT known

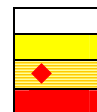






Table 53a Analog and Mixed-signal Devices Technology Requirements—Near-term **UPDATED** (continued)

[1]	Year of Production		2003	2004	2005	2006	2007	2008	2009
	Technology Node			hp90			hp65		
	DRAM ½ Pitch (nm)		100	90	80	70	65	57	50
[10]	nMOS Analog Precision Device	g_m/g_{ds} at $10 \cdot L_{min}$ -digital	300	300	300	300	300	300	300
[11]	nMOS Analog Precision Device	1/f Noise ($\mu V^2 \cdot \mu m^2/Hz$)	500	300	300	300	200	200	200
[12]	nMOS Analog Precision Device	σV_{th} matching (mV· μm)	15	12	12	12	9	9	9
[13]	Analog Capacitor	Density (fF/ μm^2)	2	3	3	3	4	4	4
[14]	Analog Capacitor	Voltage linearity (ppm/V ²)	<100	<100	<100	<100	<100	<100	<100
[15]	Analog Capacitor	Leakage (fA/[pF·V])	7	7	7	7	7	7	7
[16]	Analog Capacitor	σ Matching (%· μm)	1	0.7	0.7	0.7	0.5	0.5	0.5
[17]	Analog Resistor	Parasitic capacitance (fF/ μm^2)	0.1–0.02	0.1–0.02	0.1–0.02	0.1–0.02	0.1–0.02	0.1–0.02	0.1–0.02
[18]	Analog Resistor	Temp. linearity (ppm/°C)	50–80	40–80	40–80	40–80	30–60	30–60	30–60
[19]	Analog Resistor	1/f-current-noise per current ² (1/[$\mu m^2/Hz$])	$\leq 10^{-18}$	$\leq 10^{-18}$	$\leq 10^{-18}$	$\leq 10^{-18}$	$\leq 10^{-18}$	$\leq 6 \times 10^{-19}$	$\leq 6 \times 10^{-19}$
[20]	Analog Resistor	σ Matching (%· μm)	3	2.5	2.5	2.5	2	2	2
[21]	Bipolar Analog Device	g_m/g_{ce} at W_e -min *	1200	1150	1150	1150	1100	1100	1100
[22]	Bipolar Analog Device	1/f-noise ($\mu V^2 \cdot \mu m^2/Hz$)	5	3	3	3	2	2	2
WAS	[23]	Bipolar Analog Device	σ current matching (%· μm^2)	20	20	20	20	20	20
IS	[23]	Bipolar Analog Device	σ current matching (%· μm)	<u>2</u>	<u>2</u>	<u>2</u>	<u>2</u>	<u>2</u>	<u>2</u>

*Unusual measure for the voltage gain of bipolar devices, see notes. Added for 1:1 comparison with g_m/g_{ds} of MOS transistors (item 5).

Manufacturable solutions exist, and are being optimized 
 Manufacturable solutions are known 
 Interim solutions are known 
 Manufacturable solutions are NOT known 

4 RF and Analog/Mixed-signal Technologies for Wireless Communications

Table 53b Analog and Mixed-signal Devices Technology Requirements—Long-term [UPDATED](#)

	[1]	Year of Production	2010	2011	2012	2013	2014	2015	2016	2017	2018	
		Technology Node	hp45			hp32			hp22			
		DRAM ½ Pitch (nm)	45	40	35	32	28	25	22	20	18	
WAS	[2]	Minimum Supply Voltage	Digital design (V)	0.7		0.7	0.65		0.65	0.6	0.6	
IS	[2]	<u>nMOS Analog Speed Device</u>	Supply voltage (V)	<u>1.0</u>	<u>1.0</u>	<u>1.0</u>	0.9	<u>0.9</u>	0.8	0.8	<u>0.7</u>	0.7
WAS**	[3]	Minimum Supply Voltage	Analog design (V)	1.8–1.2	1.8–1.2	1.8–1.2	1.8–1.0		1.8–1.0	1.5–1.0	-	1.5–1.0
IS	[7]	<u>entire row MOVED**</u>	Supply voltage (V)									
WAS	[4]	NMOS Analog Speed Device	T_{ox} (nm)	0.5–0.8		0.5–0.8	0.4–0.6	-	0.4–0.6	0.4–0.5	-	0.4–0.5
IS		NMOS Analog Speed Device		<u>1.3</u>	<u>1.2</u>	<u>1.2</u>	<u>1.1</u>	<u>1.0</u>	1.0	0.9	<u>0.9</u>	0.9
WAS	[5]	NMOS Analog Speed Device	g_m/g_{ds} at $5 \cdot L_{min-digital}$	100		100	100	-	100	100	-	100
IS		NMOS Analog Speed Device		<u>100</u>	<u>100</u>	<u>100</u>	<u>100</u>	<u>100</u>	100	100	<u>100</u>	100
WAS	[6]	NMOS Analog Speed Device	$1/f$ -noise ($\mu V^2 \cdot \mu m^2 / Hz$)	150		150	100	-	100	75	-	75
IS		NMOS Analog Speed Device		150	150	150	100	<u>100</u>	100	75	<u>75</u>	75
WAS	[7]	NMOS Analog Speed Device	σV_{th} matching ($mV \cdot \mu m$)	2.5		2.5	2	-	2	1.5	-	1.5
IS		NMOS Analog Speed Device	\square	2.5	2.5	2.5	2	<u>2</u>	2	1.5	<u>1.5</u>	1.5
IS	[7]	<u>nMOS Analog Precision Device</u>	Supply voltage (V)	1.8 - 1.2	1.8 - 1.2	1.8 - 1.2	1.8 - 1.0	<u>1.8 - 1.0</u>	1.8 - 1.0	1.5 - 1.0	<u>1.5 - 1.0</u>	1.5 - 1.0
WAS	[8]	NMOS Analog Precision Device	T_{ox} (nm)	3–2		3–2	3–1.3	-	3–1.3	2.5–1.3	-	2.0–1.3
IS		NMOS Analog Precision Device		3 - 2	3 - 2	3 - 2	3 - 1.3	<u>3 - 1.3</u>	3 - 1.3	2.5 - 1.3	<u>2.5 - 1.3</u>	2.0 - 1.3
WAS	[9]	NMOS Analog Precision Device	Analog V_{th} (V)	0.3–0.2		0.3–0.2	0.3–0.2	-	0.3–0.2	0.3–0.2	-	0.3–0.2
IS		NMOS Analog Precision Device		0.3 - 0.2	0.3 - 0.2	0.3 - 0.2	0.3 - 0.2	<u>0.3 - 0.2</u>	0.3 - 0.2	0.3 - 0.2	<u>0.3 - 0.2</u>	0.3 - 0.2
WAS	[10]	NMOS Analog Precision Device	g_m/g_{ds} at $10 \cdot L_{min-digital}$	300		300	300	-	300	300	-	300
IS		NMOS Analog Precision Device		300	300	300	300	<u>300</u>	300	300	<u>300</u>	300
WAS	[11]	NMOS Analog Precision Device	$1/f$ Noise ($\mu V^2 \cdot \mu m^2 / Hz$)	200		200	150	-	150	100	-	100
IS		NMOS Analog Precision Device		200	200	200	150	<u>150</u>	150	100	<u>100</u>	100
WAS	[12]	NMOS Analog Precision Device	σV_{th} matching ($mV \cdot \mu m$)	7.5		7.5	6	-	6	5	-	5
IS		NMOS Analog Precision Device	\square	7.5	7.5	7.5	6	<u>6</u>	6	5	<u>5</u>	5

Manufacturable solutions exist, and are being optimized
 Manufacturable solutions are known
 Interim solutions are known
 Manufacturable solutions are NOT known

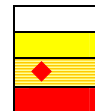
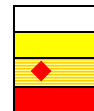


Table 53b Analog and Mixed-signal Devices Technology Requirements—Long-term **UPDATED** (continued)

[11]		Year of Production	2010	2011	2012	2013	2014	2015	2016	2017	2018	
		Technology Node	hp45			hp32			hp22			
		DRAM ½ Pitch (nm)	45	40	35	32	28	25	22	20	18	
WAS	[13]	Analog Capacitor	Density (fF/μm ²)	5		5	7	-	7	10	-	10
IS		Analog Capacitor		5	5	5	7	7	7	10	10	10
WAS	[14]	Analog Capacitor	Voltage linearity (ppm/V ²)	<100		<100	<100	-	<100	<100	-	<100
IS		Analog Capacitor		<100	<100	<100	<100	<100	<100	<100	<100	<100
WAS	[15]	Analog Capacitor	Leakage (fA/pF·V)	7		7	7	-	7	7	-	7
IS		Analog Capacitor		7	7	7	7	7	7	7	7	7
WAS	[16]	Analog Capacitor	σ Matching (%·μm)	0.4		0.4	0.3	-	0.3	0.2	-	0.2
IS		Analog Capacitor	□	0.4	0.4	0.4	0.3	0.3	0.3	0.2	0.2	0.2
WAS	[17]	Analog Resistor	Parasitic capacitance (fF/μm ²)	0.1–0.02		0.1–0.02	0.1–0.02		0.1–0.02	0.1–0.02		0.1–0.02
IS		Analog Resistor		0.1 - 0.02	0.1 - 0.02	0.1 - 0.02	0.1 - 0.02	0.1 - 0.02	0.1 - 0.02	0.1 - 0.02	0.1 - 0.02	0.1 - 0.02
WAS	[18]	Analog Resistor	Temp. linearity (ppm/°C)	30–60		30–60	30		30	30		30
IS		Analog Resistor		30 - 60	30 - 60	30 - 60	30	30	30	30	30	30
WAS	[19]	Analog Resistor	1/f-current-noise per current ² (1/[μm ² /Hz])	≤6×10 ⁻¹⁹		≤3×10 ⁻¹⁹	≤3×10 ⁻¹⁹	-	≤3×10 ⁻¹⁹	≤2×10 ⁻¹⁹	-	≤2×10 ⁻¹⁹
IS		Analog Resistor		≥ 4.5×10 ⁻¹⁹	≥ 4.5×10 ⁻¹⁹	> 4.5×10 ⁻¹⁹	> 3×10 ⁻¹⁹	≥ 3×10 ⁻¹⁹	> 3×10 ⁻¹⁹	> 2×10 ⁻¹⁹	≥ 2×10 ⁻¹⁹	> 2×10 ⁻¹⁹
WAS	[20]	Analog Resistor	σ Matching (%·μm)	1.7		1.7	1.5	-	1.5	1.2	-	1.2
IS		Analog Resistor	□	1.7	1.7	1.7	1.5	1.5	1.5	1.2	1.2	1.2
WAS	[21]	Bipolar Analog Device	g _m /g _{ce} at W _{e-min} *	1050		1050	1000	-	1000	950	-	950
IS		Bipolar Analog Device		1050	1050	1050	1000	1000	1000	950	950	950
WAS	[22]	Bipolar Analog Device	1/f-noise (μV ² ·μm ² /Hz)	1.5		1.5	1	-	1	0.7	-	0.7
IS		Bipolar Analog Device		1.5	1.5	1.5	1	1	1	0.7	0.7	0.7
WAS	[23]	Bipolar Analog Device	σ current matching (%·μm ²)	20		20	20	-	20	20	-	20
IS		Bipolar Analog Device	□	2	2	2	2	2	2	2	2	2

Manufacturable solutions exist, and are being optimized
 Manufacturable solutions are known
 Interim solutions are known
 Manufacturable solutions are NOT known



6 RF and Analog/Mixed-signal Technologies for Wireless Communications

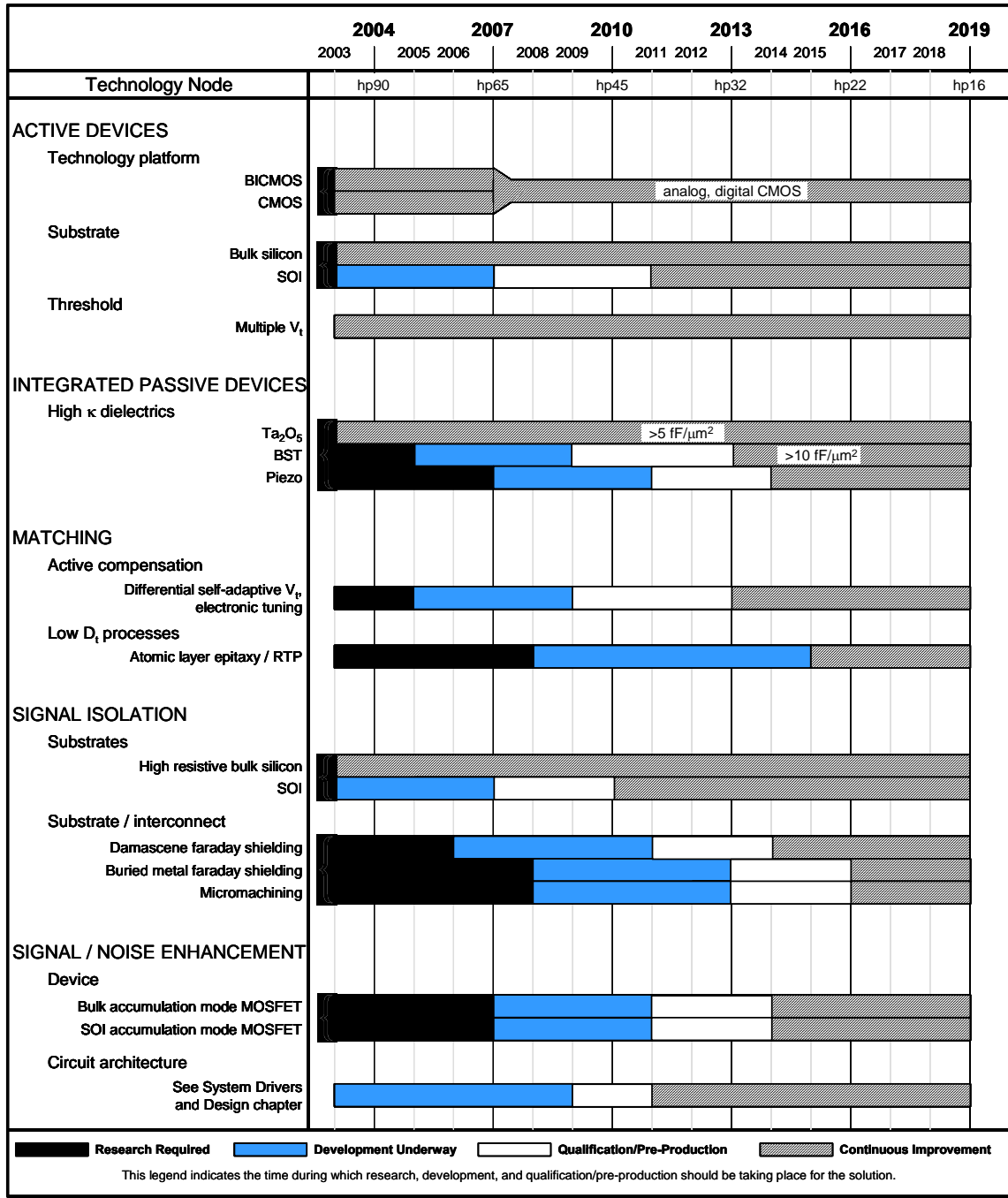
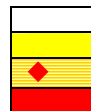


Figure 35 Analog and Mixed-signal Devices Potential Solutions [UPDATED](#)

Table 54a 0.8–10 GHz Transceiver Technology Requirements—Near-term **UPDATED**

Year of Production		2003	2004	2005	2006	2007	2008	2009
Technology Node			hp90			hp65		
DRAM ½ Pitch (nm)		100	90	80	70	65	57	50
Circuit Block—LNA								
NPN								
	V _{cc} (V)	2.5	2.5	1.8	1.8	1.5	1.5	1.5
WAS	Emitter width (µm)	0.2	0.18	0.15	0.15	0.13	0.12	0.1
IS	Emitter width (µm)	0.2	0.18	0.15	0.14	0.13	0.12	0.1
	I _c (µA/µm) [1]	75	59	43	37	28	22	16
WAS	Peak F _t (GHz) [Vbc=1v]	150	173	198	228	262	302	347
IS	Peak F _t (GHz) [Vbc=1v]	150	173	198	228	262	302	347
WAS	Peak F _{max} (GHz) [2]	180	203	239	256	295	330	387
IS	Peak F _{max} (GHz) [2]	180	203	239	256	295	330	387
WAS	NF _{min} (dB)	0.6	0.54	0.45	0.45	0.39	0.36	0.3
IS	NF _{min} (dB)	0.4	0.36	0.3	0.28	0.26	0.24	0.2
NMOS								
	V _{dd} (V)	1.5	1.3	1.3	1.3	1.2	1.2	1.1
	I _{ds} (µA/µm) [3]	26	23	21	16	12	10	9
	Peak F _t (GHz)	110	120	140	170	200	240	280
	Peak F _{max} (GHz) [2]	120	140	160	190	220	260	310
WAS	NF _{min} (dB)	0.8	0.7	0.6	0.6	0.5	0.4	0.4
IS	NF _{min} (dB) [3]	0.4	0.33	0.3	0.25	0.22	0.2	<0.2
Circuit Block Synthesizer/Logic								
CMOS								
	Gate length (nm) [4]	80	75	65	53	45	37	32
BiCMOS								
	Gate length (nm)	100	90	80	75	65	53	45
Circuit Block—VCO								
Inductor								
	Q (5 GHz) [5]	15	16	17	19	20	22	24
Varactor								
	Tuning Range [6]	3.5	3.5	3.5	3.5	3.5	3.5	3.5
	Q (5 GHz)	30	32	35	38	41	44	48

Manufacturable solutions exist, and are being optimized
 Manufacturable solutions are known
 Interim solutions are known
 Manufacturable solutions are NOT known



**8 RF and Analog/Mixed-signal Technologies
for Wireless Communications**

Table 54a 0.8–10 GHz Transceiver Technology Requirements—Near-term **UPDATED** (continued)

Year of Production	2003	2004	2005	2006	2007	2008	2009
Technology Node		hp90			hp65		
DRAM ½ Pitch (nm)	100	90	80	70	65	57	50
<i>Circuit Block—Driver</i>							
<i>System Requirements</i>							
Supply (V)	3	3	3	3	2.4	2.4	2.4
<i>HV NPN</i>							
BV _{CBO} (V)	12	12	12	12	10	10	10
Peak F _T (GHz) [Vbc=1V]	35	40	46	53	61	70	81
Peak F _{max} (GHz) [2]	80	90	106	114	131	146	172
<i>HV MOS</i>							
V _{ds} (V)	3	3	3	3	2.4	2.4	2.4
Peak F _T (GHz)	30	30	40	40	50	50	60
Peak F _{max} (GHz) [2]	35	35	45	45	55	55	65
<i>Circuit. Block—Filters/Bypass</i>							
<i>Cap</i>							
Density (fF/μm ²)	5	7	9	12	15	19	23
Q (5 GHz)	>50	>50	>50	>50	>50	>50	>50
<i>Resistor</i>							
C _{parasitic} (fF) [7]	70	63	57	51	46	41	37
TCR (ppm/C)	100	90	81	73	66	59	53
<i>Circuit. Block—Isolation</i>							
S21 dB [8]	60	70	80	90	100	110	120

NF—noise figure TCR—temperature coefficient for resistance HV—high voltage

Manufacturable solutions exist, and are being optimized

Manufacturable solutions are known

Interim solutions are known

Manufacturable solutions are NOT known

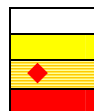
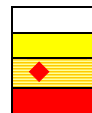


Table 54b 0.8–10 GHz Transceiver Technology Requirements—Long-term [UPDATED](#)

Year of Production		2012	2015	2018
DRAM ½ Pitch (nm)		35	25	18
Circuit Block—LNA				
NPN				
V _{cc} (V)		1.2	1.2	1.2
Emitter width (μm)		0.09	0.08	0.07
I _c (μA/μm) [1]		13	10	7
Peak F _t (GHz)		400	460	530
Peak F _{max} (GHz) [2]		438	498	572
WAS	NF _{min} (dB)	0.27	0.24	0.21
IS	NF _{min} (dB)	0.18	0.16	0.14
NMOS				
V _{dd} (V)		1	1	0.9
I _{ds} (μA/μm) [3]		7	4	1.5
Peak F _t (GHz)		400	700	1400
Peak F _{max} (GHz) [2]		450	750	1500
WAS	Nf _{min} (dB)	0.2	0.2	0.2
IS	Nf _{min} (dB) [3]	<0.2	<0.2	<0.2
Circuit Block—Synthesizer/Logic				
CMOS				
Gate length (nm) [4]		22	16	11
BiCMOS				
WAS	Gate length (nm) [4]	22	16	11
IS	Gate length (nm) [4]	25	18	13
Circuit Block—VCO				
Inductor				
Q (5 GHz)		26	28	30
Varactor				
Tuning range [6]		3.5	3.5	3.5
Q (5 GHz)		52	60	70

Manufacturable solutions exist, and are being optimized
 Manufacturable solutions are known
 Interim solutions are known
 Manufacturable solutions are NOT known

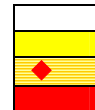


10 RF and Analog/Mixed-signal Technologies for Wireless Communications

Table 54b 0.8–10 GHz Transceiver Technology Requirements—Long-term [UPDATED](#) (continued)

<i>Year of Production</i>	<i>2012</i>	<i>2015</i>	<i>2018</i>
<i>DRAM ½ Pitch (nm)</i>	35	25	18
<i>Circuit Block—Driver</i>			
<i>System Requirements</i>			
Supply (V)	2.4	2	2
<i>HV NPN</i>			
BV _{CBO} (V)	10	8	8
Peak F _t (GHz) [Vbc=1V]	93	107	123
Peak F _{max} (GHz) [2]	195	221	254
<i>HV NMOS</i>			
BV _{DSS} (V)	2.4	2.0	2.0
Peak F _t (GHz)	60	100	100
Peak F _{max} (GHz) [2]	65	120	120
<i>Circuit Block—Filters/Bypass</i>			
<i>Cap</i>			
Density (fF/μm ²)	27	30	33
Q (5 GHz)	>50	>50	>50
<i>Resistor</i>			
C _{parasitic} (fF) [6]	33	30	27
TCR (ppm/C)	48	43	29
<i>Circuit Block—Isolation</i>			
S21 dB [7]	130	140	150

Manufacturable solutions exist, and are being optimized
Manufacturable solutions are known
Interim solutions are known
Manufacturable solutions are NOT known



Notes for Tables 54a and 54b:

- [1] I_c for F_t of 50 GHz for a minimum W_e and unit (1 μm) L_e. F_t of 50 GHz is chosen for being 10× the application frequency for 5 GHz. An application frequency of 5 GHz is chosen as a mid-point for the frequency range of interest (1–10 GHz).
- [2] Peak F_{max} (measured from unilateral gain extrapolated from 40 GHz with a 20 dB/dec slope).
- [3] I_{ds} for F_t of 50 GHz for a minimum L and unit (1 μm) W. F_t of 50 GHz is chosen for being 10× the application frequency for 5 GHz. An application frequency of 5 GHz is chosen as a mid-point for the frequency range of interest (1–10 GHz).
- [4] RF CMOS technology nodes lag low standby power (LSTP) roadmap nodes by one year.
- [5] Q at 5 GHz for a 1nH, 30,000 μm² inductor.
- [6] Defined as C_{max}/C_{min}.
- [7] Parasitic capacitance to substrate for a resistor of 1000 Ohms achieving 1% 3-sigma mismatch.
- [8] Required to achieve direct modulation of the PA in short term (2–5 GHz). Required to achieve Tx/Rx integration in WCDMA (2 GHz).

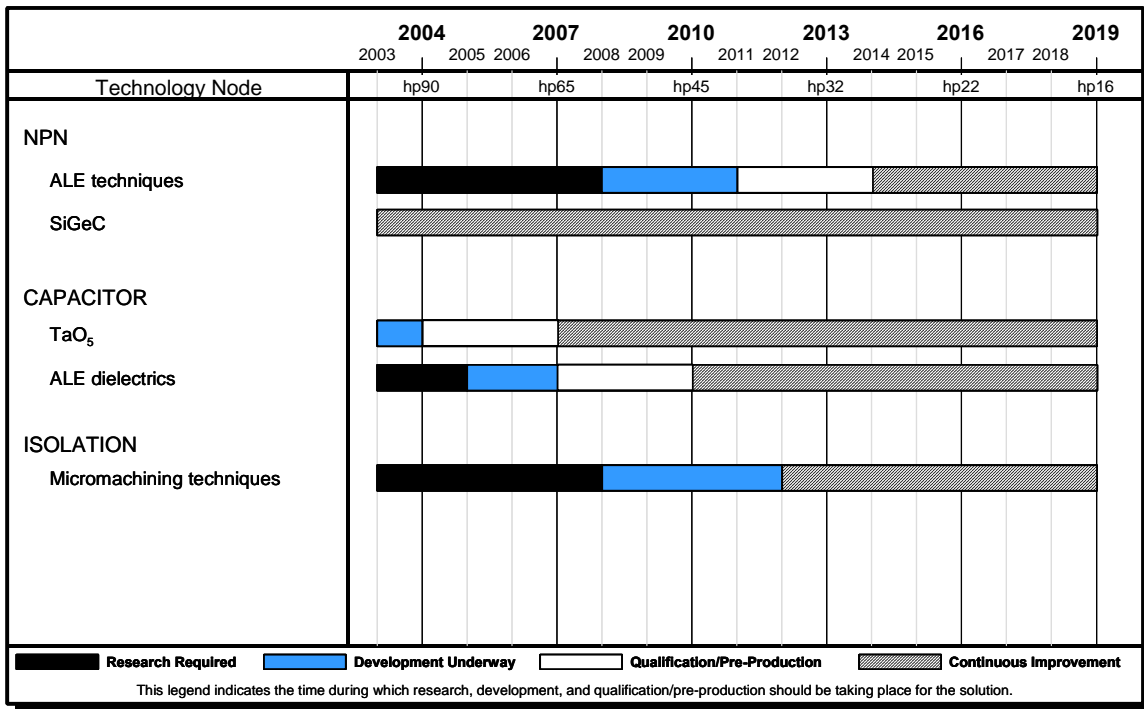


Figure 36 RF Transceivers Potential Solutions [UPDATED](#)

**12 RF and Analog/Mixed-signal Technologies
for Wireless Communications**

Table 55a Power Amplifier Technology Requirements—Near-term

Year of Production	2003	2004	2005	2006	2007	2008	2009
Technology Node		hp90			hp65		
DRAM ½ Pitch (nm)	100	90	80	70	65	57	50
Nominal PA Supply Voltage (V)	3	3			2.4		
PA Product Solutions	Integrated Module		Single Radio SIP [1]			Radio/ Baseband SIP [2]	
PA Frequency (GHz)	0.8–2.5	0.8–6			0.8–10		
<i>III-V HBT Transistor</i>							
F_{max} (at V_{cc}) (GHz)	45	45	45	45	75	75	75
BV_{CBO} (V)	25	25	25	25	18	18	18
Linear efficiency (%) [3]	52	52	52	52	55	55	55
Area (mm^2) [4]	2.5	2.5	2.5	2	2	2	2
Cost/ mm^2 (US\$) [5]	0.4	0.4	0.4	0.28	0.28	0.25	0.24
<i>III-V HBT Integration</i>							
Power management [6]	N/A	N/A	N/A	N/A	N/A	N/A	N/A
Switch [7]	N/A	N/A	N/A	N/A	N/A	N/A	N/A
Filter [8]	N/A	N/A	N/A	Yes	Yes	Yes	Yes
<i>III-V PHEMT Transistor</i>							
F_{max} (at V_{dd}) (GHz)	45	45	45	45	75	75	75
BV_{DGO} (V)	20	20	20	20	16	16	16
Linear Efficiency (%) [3]	55	55	55	55	58	58	58
PA Area (mm^2) [4]	4	4	4	3.5	3.5	3.5	3.5
Cost/ mm^2 (US\$) [5]	0.4	0.4	0.4	0.28	0.28	0.25	0.24

Manufacturable solutions exist, and are being optimized
Manufacturable solutions are known
Interim solutions are known
Manufacturable solutions are NOT known

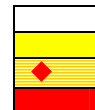
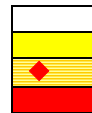


Table 55a Power Amplifier Technology Requirements—Near-term (continued)

Year of Production	2003	2004	2005	2006	2007	2008	2009
Technology Node		hp90			hp65		
DRAM ½ Pitch (nm)	100	90	80	70	65	57	50
III-V PHEMT Integration							
Power management [6]	N/A	N/A	N/A	N/A	N/A	N/A	N/A
Switch [7]	N/A	N/A	Yes	Yes	Yes	Yes	Yes
Filter [8]	N/A	N/A	N/A	Yes	Yes	Yes	Yes
III-V Passives							
Inductors Q [9]	15	15	15	25	25	25	25
Capacitor Q [10]	>100	>100	>100	>100	>100	>100	>100
Bypass capacitor density (fF/μm ²) [12]	0.6	0.6	0.6	2	2	2	2
RF capacitor density (fF/μm ²) [13]	0.6	0.6	0.6	2	2	2	2
Silicon MOSFET Transistor							
T _{ox} (PA) (Å) [11]	60	60	60	45	45	45	35
F _{max} (at V _{dd})	45	45	45	60	60	60	75
BV _{DSS} (V)	12	12	12	10	10	10	8
Linear efficiency (%) [3]	45	45	45	50	50	50	52
PA Area (mm ²) [4]	6	6	6	4.5	4.5	4.5	3
Cost/mm ² (US\$) [5]	0.1	0.08	0.08	0.06	0.06	0.06	0.05
Silicon MOSFET Integration							
Power management [8]	Yes	Yes	Yes	Yes	Yes	Yes	Yes
Switch [9]	NO	NO	NO	MEMS	MEMS	MEMS	MEMS
Filter [10]	NO	NO	NO	MEMS	MEMS	MEMS	MEMS
SiGe HBT Transistor							
F _{max} (GHz)	45	60	60	80	80	80	80
BV _{CBO} (V)	18	18	18	16	16	12	12
Linear efficiency (%) [3]	50	50	50	55	55	55	55
PA Area (mm ²) [4]	2.5	2.2	2.2	2	2	1.7	1.7
Cost/mm ² (US\$) [5]	0.15	0.15	0.12	0.12	0.11	0.11	0.11
SiGe Integration							
Power management	Yes	Yes	Yes	Yes	Yes	Yes	Yes
Switch	NO	NO	MEMS	MEMS	MEMS	MEMS	MEMS
Filter	NO	NO	MEMS	MEMS	MEMS	MEMS	MEMS
Silicon / SiGe Passives							
Inductors Q [9]	10	10	10	14	14	14	14
Capacitor Q [10]	>100	>100	>100	>100	>100	>100	>100
Bypass capacitor density (fF/μm ²) [12]	2	4	4	20	20	30	30
RF capacitor density (fF/μm ²) [13]	2	4	4	6	6	8	8

Manufacturable solutions exist, and are being optimized
 Manufacturable solutions are known
 Interim solutions are known
 Manufacturable solutions are NOT known



**14 RF and Analog/Mixed-signal Technologies
for Wireless Communications**

Table 55b Power Amplifier Technology Requirements—Long-term

<i>Year of Production</i>	2010	2012	2013	2015	2016	2018
<i>Technology Node</i>	hp45		hp32		hp22	
<i>DRAM ½ Pitch (nm)</i>	45	35	32	25	22	18
<i>Nominal PA Supply Voltage (V)</i>	2.4	2.4	2.4	2	2	2
<i>PA Product Solutions</i>	Radio/Baseband SIP [2]					
<i>PA Frequency (GHz)</i>	0.8–10 GHz					
<i>III-V HBT Transistor</i>						
<i>F_{max} (at V_{cc}) (GHz)</i>	75	75	75	75	75	75
<i>BV_{CBO} (V)</i>	18	18	18	18	18	18
<i>Linear efficiency (%) [3]</i>	55	55	55	55	55	55
<i>Area (mm²) [4]</i>	2	1.8	1.8	1.8	1.8	1.8
<i>Cost/mm² (US\$) [5]</i>	0.24	0.22	0.2	0.15	0.15	0.15
<i>III-V HBT Integration</i>						
<i>Power management [6]</i>	N/A	N/A	N/A	N/A	N/A	N/A
<i>Switch [7]</i>	N/A	N/A	N/A	N/A	N/A	N/A
<i>Filter [8]</i>	Yes	Yes	Yes	Yes	Yes	Yes
<i>III-V PHEMT Transistor</i>						
<i>F_{max} (at V_{dd}) (GHz)</i>	75	75	75	75	75	75
<i>BV_{DGO} (V)</i>	16	16	16	16	16	16
<i>Linear efficiency (%) [3]</i>	58	58	58	58	58	58
<i>PA Area (mm²) [4]</i>	3.5	3	3	3	3	3
<i>Cost/mm² (US\$) [5]</i>	0.24	0.22	0.2	0.15	0.15	0.15
<i>III-V PHEMT Integration</i>						
<i>Power management [6]</i>	N/A	N/A	N/A	N/A	N/A	N/A
<i>Switch [7]</i>	Yes	Yes	Yes	Yes	Yes	Yes
<i>Filter [8]</i>	Yes	Yes	Yes	Yes	Yes	Yes
<i>III-V Passives</i>						
<i>Inductors Q [9]</i>	25	30	30	30	30	30
<i>Capacitor Q [10]</i>	>100	>100	>100	>100	>100	>100
<i>Bypass capacitor density (fF/μm²) [12]</i>	2	2	2	2	2	2
<i>RF capacitor density (fF/μm²) [13]</i>	2	2	2	2	2	2

Manufacturable solutions exist, and are being optimized

Manufacturable solutions are known

Interim solutions are known

Manufacturable solutions are NOT known

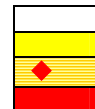
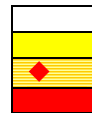


Table 55b Power Amplifier Technology Requirements—Long-term (continued)

Year of Production	2010	2012	2013	2015	2016	2018
Technology Node	hp45		hp32		hp22	
DRAM ½ Pitch (nm)	45	35	32	25	22	18
<i>Silicon MOSFET Transistor</i>						
T_{ox} (PA) (Å) [11]	35	35	35	35	35	35
F_{max} (at V_{dd})	75	75	75	35	35	35
BV_{DSS} (V)	8	8	8	2	2	2
Linear efficiency (%) [3]	52	52	52			
PA Area (mm^2) [4]	3	3	3	1.5	1.5	1.5
Cost/ mm^2 (US\$) [5]	0.05	0.05	0.05			
<i>Silicon MOSFET Integration</i>						
Power management [8]	Yes	Yes	Yes	Yes	Yes	Yes
Switch [9]	MEMS	MEMS	MEMS	MEMS	MEMS	MEMS
Filter [10]	MEMS	MEMS	MEMS	MEMS	MEMS	MEMS
<i>SiGe HBT Transistor</i>						
F_{max} (GHz)	80	80	80	TBD	TBD	TBD
BV_{CBO} (V)	12	12	10	10	10	10
Linear efficiency (%) [3]	55	55	55	TBD	TBD	TBD
PA Area (mm^2) [4]	1.7	1.5	1.5	TBD	TBD	TBD
Cost/ mm^2 (US\$) [5]	0.11	0.1	0.1	TBD	TBD	TBD
<i>SiGe Integration</i>						
Power management	Yes	Yes	Yes	Yes	Yes	Yes
Switch	MEMS	MEMS	MEMS	MEMS	MEMS	MEMS
Filter	MEMS	MEMS	MEMS	MEMS	MEMS	MEMS
<i>Silicon / SiGe Passives</i>						
Inductors Q [9]	14	18	18	18	18	18
Capacitor Q [10]	>100	>100	>100	>100	>100	>100
Bypass capacitor density ($fF/\mu m^2$) [12]	30	40	40	40	40	40
RF capacitor density ($fF/\mu m^2$) [13]	8	10	15	20	20	20

Manufacturable solutions exist, and are being optimized
 Manufacturable solutions are known
 Interim solutions are known
 Manufacturable solutions are NOT known



16 RF and Analog/Mixed-signal Technologies for Wireless Communications

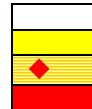
Notes for Tables 55a and 55b:

- [1] Single radio SIP—system-in-package implementation of a complete post-baseband radio design, including power management, transceiver, power amplifier, filters, and switch functions.
- [2] Radio/baseband SIP—system-in-package implementation of a complete baseband and radio design, including [1].
- [3] Linear efficiency—power added efficiency of the final PA stage under personal communication service (PCS) CDMA (IS-95) modulation.
- [4] Area—total semiconductor area necessary for the implementation of the quad-band GSM/general packet radio service (GPRS)/ Enhanced Data rates for GSM Evolution (EDGE) PA function, including matching/filtering.
- [5] Cost/mm²—approximate commercial foundry cost of the area mentioned in [4].
- [6] Power management—capability of the technology to provide RF power detection/DC power management for the PA.
- [7] Switch—capability of the technology to integrate cost-effectively a transmit/receive switch into the PA active die.
- [8] Filter—capability of the technology to integrate high-quality band selection filters needed for the assumed PA solution; currently performed with surface acoustic wave (SAW) filter technology.
- [9] Inductor Q —quality factor of a 5nH inductor at 1 GHz achievable with the technology with a metallization suitable for handling the power requirements of the PA.
- [10] Capacitor Q —quality factor of a 10pF capacitor at 1 GHz achievable with the technology. Capacitor breakdown voltage must be rated for appropriate power amplification function.
- [11] $T_{ox}(PA)$ —thickness of the MOSFET transistor in the RF power amplifier function.
- [12] Bypass capacitor density—bypass capacitor connected between V_{dd} (or V_{cc}) and ground. Capacitor breakdown voltage must be rated for appropriate power amplification function.
- [13] RF capacitor density—capacitor used for all other functions (matching, harmonic filtering, coupling, etc). Capacitor must have adequate breakdown for the given application.

Table 56a Base Station Devices Technology Requirements—Near-term **UPDATED**

	2003	2004	2005	2006	2007	2008	2009
<i>Year of Production</i>	2003	2004	2005	2006	2007	2008	2009
<i>Technology Node</i>		hp90			hp65		
<i>DRAM ½ Pitch (nm)</i>	100	90	80	70	65	57	50
<i>Application frequency (GHz)</i>	0.8–2	0.8–2.7			0.8–3.5		
WAS <i>Cost (\$\$/Watt)</i>	1	0.9	0.8	0.7	0.6	0.5	
IS <i>Cost (\$\$/Watt)</i>	1	0.8	0.7	0.6	0.5	0.4	
<i>Packaging (C-Ceramic, P-Plastic)</i>	C/P	C/P	C/P	Plastic			
<i>Si LDMOS</i>							
<i>Operating voltage (V)</i>	28	28	<40	<40	<50	<50	<50
<i>Saturated power (Watt)</i>	240	240	240	240	240	240	240
WAS <i>Saturated power density (W/mm)</i>	0.7	0.7	0.9	0.9	1.2	1.2	1.2
IS <i>Saturated power density (W/mm)</i>	0.7	0.8	1	1.2	1.4	1.4	1.4
<i>Saturated PAE (%)</i>	60	63	65	68	65	68	70
WAS <i>Linear power (Watt)</i>	120	120	120	120	120	120	120
IS <i>Linear power (Watt)</i>	<120	<120	<120	<120	<120	<120	<120
<i>Linear PAE (%)</i>	45	48	50	52	50	52	54
<i>GaAs FET</i>							
WAS <i>Operating voltage (V)</i>	12	12	12	28	28	28	28
IS <i>Operating voltage (V)</i>	12	12	28	28	28	28	28
<i>Saturated power (Watt)</i>	180	180	180	180	180	180	180
WAS <i>Saturated power density (W/mm)</i>	0.7	0.7	0.7	1	1.2	1.5	1.5
IS <i>Saturated power density (W/mm)</i>	0.7	0.7	1	1.2	1.5	1.8	1.8
<i>Saturated PAE (%)</i>	65	65	68	70	68	70	72
WAS <i>Linear power (Watt)</i>	90	90	90	90	90	90	90
IS <i>Linear power (Watt)</i>	<90	<90	<90	<90	<90	<90	<90
<i>Linear PAE (%)</i>	50	50	52	55	57	55	57
<i>SiC FET</i>							
<i>Operating voltage (V)</i>	48	48	48	48	48	48	48
<i>Saturated power (Watt)</i>	10	30	60	60	60	60	60
WAS <i>Saturated power density (W/mm)</i>	2	2	2	2	2	2	2
IS <i>Saturated power density (W/mm)</i>	2		3	3	3	3	3
WAS <i>Saturated PAE (%)</i>	45	45	45	45	45	45	45
IS <i>Saturated PAE (%)</i>	45	45	45	45	47	47	47
<i>GaN FET</i>							
<i>Operating voltage (V)</i>	-	-	28	28	48	48	48
WAS <i>Saturated power (Watt)</i>	-	-	10	30	60	60	180
IS <i>Saturated power (Watt)</i>	-	-	30	30	60	60	180
WAS <i>Saturated power density (W/mm)</i>	-	-	2	2	4	4	4
IS <i>Saturated power density (W/mm)</i>	-	-	3	3	5	5	5
<i>Saturated PAE (%)</i>	-	-	52	55	50	52	55

Manufacturable solutions exist, and are being optimized
 Manufacturable solutions are known
 Interim solutions are known
 Manufacturable solutions are NOT known



**18 RF and Analog/Mixed-signal Technologies
for Wireless Communications**

Table 56b Base Station Devices Technology Requirements—Long-term UPDATED

Year of Production		2010	2011	2012	2013	2014	2015	2016	2017	2018
Technology Node		hp45			hp32			hp22		
DRAM ½ Pitch (nm)		45	40	35	32	28	25	22	20	18
Application frequency (GHz)		0.8–5								
WAS	Cost (\$\$/Watt)	0.4				0.3				
IS	Cost (\$\$/Watt)	0.3				0.25				
Packaging (C–Ceramic, P–Plastic)		Plastic								
Si LDMOS										
Operating voltage (V)		<50		<50	<50		<50	<50		<50
Saturated power (Watt)		240		240	240		240	240		240
WAS	Saturated power density (W/mm)	1.2		1.2	1.2		1.2	1.2		1.2
IS	Saturated power density (W/mm)	1.4	-	1.4	1.4	-	1.4	1.4	-	1.4
Saturated PAE (%)		65		65	70		70	70		70
WAS	Linear power (Watt)	120		120	120		120	120		120
IS	Linear power (Watt)	<120	-	<120	<120	-	<120	<120	-	<120
Linear PAE (%)		50		50	52		52	52		52
GaAs FET										
Operating voltage (V)		28		28	28		28	28		28
Saturated power (Watt)		180		180	180		180	180		180
WAS	Saturated power density (W/mm)	1.5		1.5	1.5		1.5	1.5		1.5
IS	Saturated power density (W/mm)	1.8	-	1.8	1.8	-	1.8	1.8	-	1.8
Saturated PAE (%)		68		68	70		70	72		72
WAS	Linear power (Watt)	90		90	90		90	90		90
IS	Linear power (Watt)	<90	-	<90	<90	-	<90	<90	-	<90
Linear PAE (%)		52		52	55		55	57		57
SiC FET										
Operating voltage (V)		48		48	48		48	48		48
Saturated power (Watt)		60		60	60		60	60		60
WAS	Saturated power density (W/mm)	2		2	2		2	2		2
IS	Saturated power density (W/mm)	3	-	3	3	-	3	3	-	3
WAS	Saturated PAE (%)	45		45	45		45	45		45
IS		47	-	47	47	-	47	47	-	47
GaN FET										
Operating voltage (V)		48		48	48		48	48		48
Saturated power (Watt)		180		180	180		180	180		180
WAS	Saturated power density (W/mm)	4		4	4		4	4		4
IS	Saturated power density (W/mm)	5	-	5	5	-	5	5	-	5
Saturated PAE (%)		50		50	52		52	55		55

Manufacturable solutions exist, and are being optimized
Manufacturable solutions are known
Interim solutions are known
Manufacturable solutions are NOT known

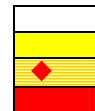


Table 57 Millimeter Wave 10–100 GHz Technology Requirements—Near-term **UPDATED**

Year of Production	2003	2004	2005	2006	2007	2008	2009
Technology Node		hp90			hp65		
DRAM ½ Pitch (nm)	100	90	80	70	65	57	50
Device Technology—FET *							
GaAs MESFET (digital mixed-signal)							
Gate length—L physical (nm)	250	250	150	150	-	-	-
Minimum M1 pitch (nm)	1200	1200	680	680	-	-	-
F ₁ - enhancement mode (GHz)	80	80	120	120	-	-	-
F ₁ - depletion mode (GHz)	70	70	100	100	-	-	-
BV _{GD} (1mA/mm, V _g =0) (volts)	7.5	7.5	5 to 10	5 to 10	-	-	-
Power delay product at gate delay-FO=1 (fJ at pS)	2 at 25	2 at 25	1.2 at 18	1.2 at 18	-	-	-
Shortest DCFL gate delay (pS)	10	10	6	6	-	-	-
Interconnect metal layers	4	4	5	5	-	-	-
Interconnect metal	Al	Al	Al	Al	-	-	-
Inter line dielectric constant (effective)	4.2	4.2	3.1	3.1	-	-	-
GaAs PHEMT (low noise)							
Gate length (nm)	100	100	70	70	50	50	32
F ₁ (GHz)	130	130	150	150	170	170	200
Breakdown (volts)	7	7	7	7	6	6	5.5
I _{max} (mA/mm)	650	650	600	600	550	550	550
G _m (S/mm)	0.65	0.65	0.8	0.8	0.9	0.9	1
NF (dB) at 26 GHz, 18–20 dB associated gain	3.1	3.1	2.5	2.5	2	2	1.5
NF (dB) at 94 GHz, 8–10 dB associated gain	4.8	4.8	4	4	3.5	3.5	3
GaAs PHEMT (power)							
Gate length (nm)	200	200	100	100	70	70	-
F _{max} (GHz)	75	75	150	150	200	200	-
Breakdown (volts)	11	11	11	11	9	9	-
I _{max} (ma/mm)	650	650	750	750	850	850	-
G _m (S/mm)	0.52	0.52	0.67	0.67	0.85	0.85	-
P _{out} at 26 GHz and peak efficiency (mW/mm)	500	500	550	550	600	600	-
Peak efficiency at 26 GHz (%)	20	20	30	30	40	40	-
Gain at 26 GHz, at P _{1dB} (dB)***	10	10	12	12	14	14	-
P _{out} at 94 GHz and peak efficiency (mW/mm)	250	250	-	-	-	-	-
Peak efficiency at 94 GHz (%)	15	15	-	-	-	-	-
Gain at 94 GHz, at P _{1dB} (dB)***	6	6	-	-	-	-	-

DCFL—direct-coupled FET logic

* Lithography dimensions are drawn dimensions.

** Output power at peak efficiency is generally at 2 to 3 dB into compression; P_{out} is normalized to total gate periphery.

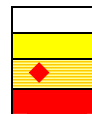
*** P_{1dB} (dB) is the point at which the device gain is 1 dB less than the linear gain, i.e., the gain is compressed by 1 dB.

Manufacturable solutions exist, and are being optimized

Manufacturable solutions are known

Interim solutions are known

Manufacturable solutions are NOT known



20 RF and Analog/Mixed-signal Technologies for Wireless Communications

Table 57 Millimeter Wave 10–100 GHz Technology Requirements—Near-term **UPDATED** (continued)

Year of Production	2003	2004	2005	2006	2007	2008	2009
Technology Node		hp90			hp65		
DRAM ½ Pitch (nm)	100	90	80	70	65	57	50
Device Technology—FET *							
InP HEMT (low noise)							
Gate length (nm)	-	100	70	70	50	50	32
F _t (GHz)	-	200	240	240	300	300	350
Breakdown (volts)	-	4	3.5	3.5	3	3	2.5
I _{max} (ma/mm)	-	700	700	700	650	650	600
G _m (S/mm)	-	1	1.2	1.2	1.5	1.5	1.8
NF (dB) at 26 GHz, 20–23 dB associated gain	-	2.2	1.8	1.8	1.5	1.5	1.2
NF (dB) at 94 GHz, 10–13 dB associated gain	-	3	2.5	2.5	2	2	1.8
InP HEMT (power)							
Gate length (nm)	-	-	150	100	100	100	100
F _{max} (GHz)	-	-	200	220	260	260	260
Breakdown (volts)	-	-	5	5	6	6	6
I _{max} (ma/mm)	-	-	750	700	650	650	650
G _m (S/mm)	-	-	0.8	0.9	0.9	0.9	0.9
P _{out} at 26 GHz and peak efficiency (mW/mm)	-	-	400	400	450	450	450
Peak efficiency at 26 GHz (%)	-	-	30	40	50	50	50
Gain at 26 GHz, at P _{1dB} (dB)***	-	-	12	15	15	16	16
P _{out} at 94 GHz and peak efficiency (mW/mm)	-	-	250	300	350	350	400
Peak efficiency at 94 GHz (%)	-	-	25	40	40	45	45
Gain at 94 GHz, at P _{1dB} (dB)***	-	-	6	8	10	10	12
GaAs MHEMT (low noise)							
Gate length (nm)	-	-	100	100	70	70	50
F _t (GHz)	-	-	250	250	300	300	400
Breakdown (volts)	-	-	5	5	4	4	3
I _{max} (ma/mm)	-	-	680	680	680	680	680
G _m (S/mm)	-	-	1	1	1	1	1
NF (dB) at 26 GHz, 10–23 dB associated gain	-	-	1.6	1.6	1.2	1.2	0.8
NF (dB) at 94 GHz, 10–13 dB associated gain	-	-	2.3	2.3	1.8	1.8	1.6

* Lithography dimensions are drawn dimensions.

** Output power at peak efficiency is generally at 2 to 3 dB into compression; P_{out} is normalized to total gate periphery.

*** P_{1dB} (dB) is the point at which the device gain is 1 dB less than the linear gain, i.e., the gain is compressed by 1 dB.

Manufacturable solutions exist, and are being optimized

Manufacturable solutions are known

Interim solutions are known

Manufacturable solutions are NOT known

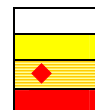


Table 57 Millimeter Wave 10–100 GHz Technology Requirements—Near-term **UPDATED** (continued)

Year of Production	2003	2004	2005	2006	2007	2008	2009
Technology Node		hp90			hp65		
DRAM ½ Pitch (nm)	100	90	80	70	65	57	50
Device Technology—FET *							
GaAs MHEMT (Power)							
Gate length (nm)	-	-	-	200	100	100	100
F _{max} (GHz)	-	-	-	200	250	275	300
Breakdown (volts)	-	-	-	8	8	8	9
I _{max} (ma/mm)	-	-	-	600	600	600	600
G _m (S/mm)	-	-	-	0.8	0.9	0.9	0.9
P _{out} at 26 GHz and peak efficiency (mW/mm)	-	-	-	350	500	600	750
Peak efficiency at 26 GHz (%)	-	-	-	45	55	55	60
Gain at 26 GHz, at P _{1dB} (dB)***	-	-	-	12	15	16	16
P _{out} at 94 GHz and peak efficiency (mW/mm)	-	-	-	200	350	400	450
Peak efficiency at 94 GHz (%)	-	-	-	25	40	45	45
Gain at 94 GHz, at P _{1dB} (dB)***	-	-	-	6	8	10	12
GaN HEMT (low noise)							
Gate length (nm)	-	-	-	-	150	100	100
F _t (GHz)	-	-	-	-	100	100	120
Breakdown (volts)	-	-	-	-	>40	60	60
I _{max} (ma/mm)	-	-	-	-	>1000	1200	1500
G _m (S/mm)	-	-	-	-	>0.3	0.4	0.5
NF (dB) at 26 GHz, 14 dB gain	-	-	-	-	2	2	1.5
GaN HEMT (power)							
Gate length (nm)	-	-	-	-	150	100	100
F _{max} (GHz)	-	-	-	-	100	100	150
Breakdown (volts)	-	-	-	-	>40	60	60
I _{max} (ma/mm)	-	-	-	-	>1000	1200	1500
G _m (S/mm)	-	-	-	-	>0.3	0.4	0.5
P _{out} at 26 GHz and peak efficiency (mW/mm)	-	-	-	-	3000	5000	5000
Peak efficiency at 26 GHz (%)	-	-	-	-	35	40	50
Gain at 26 GHz, at P _{1dB} (dB)***	-	-	-	-	10	12	12

* Lithography dimensions are drawn dimensions.

** Output power at peak efficiency is generally at 2 to 3 dB into compression; P_{out} is normalized to total gate periphery.

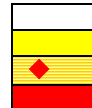
*** P_{1dB} (dB) is the point at which the device gain is 1 dB less than the linear gain, i.e., the gain is compressed by 1 dB.

Manufacturable solutions exist, and are being optimized

Manufacturable solutions are known

Interim solutions are known

Manufacturable solutions are NOT known



22 RF and Analog/Mixed-signal Technologies for Wireless Communications

Table 57 Millimeter Wave 10–100 GHz Technology Requirements—Near-term **UPDATED** (continued)

Year of Production	2003	2004	2005	2006	2007	2008	2009	
Technology Node		hp90			hp65			
DRAM ½ Pitch (nm)	100	90	80	70	65	57	50	
Device Technology—HBT *								
InP HBT								
WAS	Emitter width (nm)	1200	800	350	350	250	250	150
IS	Emitter width (nm)	1200	800	<u>350</u>	<u>350</u>	250	250	150
WAS	F _T (GHz)	170	170	300	300	300	300	400
IS	F _T (GHz)	170	170	<u>300</u>	<u>300</u>	<u>350</u>	<u>350</u>	400
WAS	F _{max} (GHz)	170	200	300	300	350	350	450
IS	F _{max} (GHz)	170	200	<u>300</u>	<u>300</u>	<u>400</u>	<u>400</u>	450
WAS	Breakdown (BV _{CEO}) (volts)	7	7	4	4	4	4	3
IS	Breakdown (BV _{CEO}) (volts)	7	7	<u>4</u>	<u>4</u>	4	4	3
WAS	I _{max} /μm ² (mA/μm ²)	1.5	2	5	4	4	4	5
IS	I _{max} /μm ² (mA/μm ²)	1.5	2	<u>4</u>	<u>5</u>	<u>5</u>	<u>5</u>	<u>7</u>
WAS	Beta	20	50	50	50	50	50	50
IS	Beta	20	50	<u>50</u>	<u>50</u>	50	50	50
WAS	3 sigma V _{BE} (mV)	50	40	40	30	30	25	25
IS	3 sigma V _{BE} (mV)	50	40	<u>40</u>	<u>30</u>	30	25	25
	Interconnect metal layers	3	4	4	4	5	5	5
WAS	Interconnect metal	Al, Au	Al, Au	Al, Au	Al, Au	Cu	Cu	Cu
IS	Interconnect metal	Al, Au	Al, Au	Al, Au	Al, Au	<u>Al, Au, Cu</u>	<u>Al, Au, Cu</u>	<u>Al, Au, Cu</u>
	Barrier	PVD	PVD	PVD	PVD	IMP	IMP	IMP
	Wafer diameter (mm)	100	100	100	100	150	150	150
SiGe HBT								
	Emitter Width (nm)	200	150	120	120	100	100	70
	F _T (GHz)	150	175	200	230	265	300	350
	F _{max} (GHz)	180	205	240	260	300	330	390
	Breakdown (BV _{CBO}) (volts)	6	5.5	5.3	5	5	4.5	4.5
	Breakdown (BV _{CEO}) (volts)	2.3	2	2	2	1.8	1.8	1.8
	I _{max} /μm ² (mA/μm ²)	7	8	10	14	14	18	18
	Beta	140	200	200	200	250	250	300
	Nf _{min} at 77 GHz (dB)	6.6	6.1	5.5	5.1	4.6	4.3	3.9

*Lithography dimensions are drawn dimensions.

** Output power at peak efficiency is generally at 2 to 3 dB into compression; P_{out} is normalized to total gate periphery.

*** P_{1dB} (dB) is the point at which the device gain is 1 dB less than the linear gain, i.e., the gain is compressed by 1 dB.

Manufacturable solutions exist, and are being optimized

Manufacturable solutions are known

Interim solutions are known

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